Abstracts

Micromachined RF MEMS tunable capacitors using piezoelectric actuators

J.Y. Park, Y.J. Yee, H.J. Nam and J.U. Bu. "Micromachined RF MEMS tunable capacitors using piezoelectric actuators." 2001 MTT-S International Microwave Symposium Digest 01.3 (2001 Vol. III [MWSYM]): 2111-2114 vol.3.

In this paper, RF MEMS tunable capacitors with low operation voltage, high linearity, high quality factor, and large tuning ratio have been fabricated by utilizing micromachined piezoelectric actuators. The fabricated tunable capacitor has a C/sub max//C/sub min/ ratio of 3.1 to 1 at bias voltages of 6 V and a quality factor of 210 at 1 GHz.

❑ Return to main document.

Click on title for a complete paper.